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Rec'd. - 8 JUL 2004

Action by.....

Datum/Date

08.07.04

Zeichen/Ref./Réf. N.87181A JGL	Anmeldung Nr./Application No./Demande n°./Patent Nr./Patent No./Brevet n°. 04251739.1-1226-
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Anmelder/Applicant/Demandeur/Patentinhaber/Proprietor/Titulaire
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COMMUNICATION

The European Patent Office herewith transmits as an enclosure the European search report for the above-mentioned European patent application.

If applicable, copies of the documents cited in the European search report are attached.

Additional set(s) of copies of the documents cited in the European search report is (are) enclosed as well.

The following specifications given by the applicant have been approved by the Search Division:

abstract title

The abstract was modified by the Search Division and the definitive text is attached to this communication.

The following figure will be published together with the abstract:

3

REFUND OF THE SEARCH FEE

If applicable under Article 10 Rules relating to fees, a separate communication from the Receiving Section on the refund of the search fee will be sent later.





European Patent
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EUROPEAN SEARCH REPORT

Application Number

EP 04 25 1739

DOCUMENTS CONSIDERED TO BE RELEVANT

Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int.Cl.7)
X	EP 1 041 607 A (NIPPON KOGAKU KK) 4 October 2000 (2000-10-04) * abstract * * figures 1-3 * * paragraph '0002! * * paragraph '0030! - paragraph '0066! * -----	1-10	G03F7/20
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A	EP 1 107 068 A (ASM LITHOGRAPHY BV) 13 June 2001 (2001-06-13) * abstract * * figures 1,2 * * paragraph '0001! - paragraph '0002! * * paragraph '0007! - paragraph '0015! * * paragraph '0026! - paragraph '0032! * -----	2,3	
TECHNICAL FIELDS SEARCHED (Int.Cl.7)			
H01L G03F			
The present search report has been drawn up for all claims			
2	Place of search The Hague	Date of completion of the search 2 July 2004	Examiner Andersen, O
CATEGORY OF CITED DOCUMENTS			
X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document			
T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document			

**ANNEX TO THE EUROPEAN SEARCH REPORT
ON EUROPEAN PATENT APPLICATION NO.**

EP 04 25 1739

This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report.
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ABSTRACT / ZUSAMMENFASSUNG / ABREGE

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In a projection system (PL) for EUV, the positions of mirrors (M1-M6) are measured and controlled relative to each other, rather than to a reference frame. Relative position measurements may be made by interferometers or capacitive sensors (IF3-IF9) mounted on rigid extensions of the mirrors.